

Office of the Dean Research and Development
Indian Institute of Engineering Science & Technology
(IIEST), Shibpur
Howrah-711 103

Project Code: DRC/DST/CEGESS/HS/022/16-17

Centre of Excellence for Green Energy & Sensor Systems
Indian Institute of Engineering Science & Technology
(IIEST), Shibpur
Howrah-711 103

Notice Inviting Quotations

Sealed quotations are invited for the supply of

Item 1. Vacuum wand to Handle 6inch wafers.

Item 2. wafers carrier.

as per the following technical specification. The technical specification can be downloaded from the website. The document can be also obtained from the Centre of Excellence for Green Energy & Sensor Systems (contact : Prof. H. Saha) between 10.00 a.m. and 6.00 p.m. on all working days. The invitation is valid for 7 working days from the date of publication of this notice .

Dean (R & D)

(A. Code:)

SECTION I: TERMS & CONDITIONS

1. The last date of receipt of quotation is valid **for 7 working days** from the date of publication of this notice. Quotations received later will not be entertained under any circumstances.
2. Potential supplier are to submit the quotations in Sealed Cover to the Centre of Excellence for Green Energy & Sensor Systems in the following address:

**Prof. H. Saha
CEGESS
IEST, Shibpur
Howrah-711103, India**

3. Item name must be mentioned on cover.
4. The price quoted should be inclusive of all Taxes in INR, duties and levies. Inclusion of Tax/Levy at a latter stage will not be accepted. Freight, Insurance charges should be clearly indicated. If GST is chargeable then price quoted should be inclusive of GST in INR (Only for Indian Manufacturers).
5. Vendor should have proven track record of supply in IEST, IIT, NIT, IISc.
6. Commercial Papers duly signed & must be attached.
7. For Foreign Suppliers : Price should be include Packing + Insurance + Shipping + Custom Duty + Custom Clearance upto IEST, Shibpur. Custom duty and Clearance charges will not be paid by IEST, Shibpur.

SECTION II: TECHNICAL SPECIFICATIONS :-

Item 1.

Vacuum wand to Handle 6inch wafers :

Vacuum wand for wafer handling with PTFE (Teflon) body. With one Quartz tip and one PEEK tip to handle up to 6 inch square wafers. Normally open valve operation (press button to pick up the wafer). X style tip extension allows the tip to be rotated and swivelled up to 30° and then locked in position for use. This system must be including necessary coil tube and adaptor.

Item 2. wafers carrier :

PVDF make wafers carrier along with download holder which can be used in Base and Alkali medium, and suitable for 156 x 156 mm square substrate, wafers handle capacity of the carrier will 25nos. The carrier will make minimum surface contact with the wafers.